

**INFORMATION DISCLOSURE
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Hubert Benzal et al.

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2818

U. S. PATENT DOCUMENTS

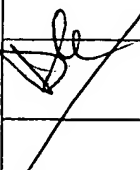
EXAMINER INITIAL	PATENT NUMBER	PATENT DATE	NAME	CLASS	SUBCLASS	FILING DATE*

* - If pertinent

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
	1 088 785	April 4, 2001	EP			X	
	100 46 622	April 4, 2002	DE			X	
	WO 03/016203	Feb. 27, 2003	PCT			X	
	WO 02/36484	May 10, 2002	PCT			X	

OTHER DOCUMENTS

EXAMINER INITIAL	AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.
	R.W Tjeskstra et al. "Multi-walled Microchannels: Free-standing Porous Silicon Membrane For Use In Mu TAS", Journal of Microelectromechanical Systems, IEEE INC., Bd. 9 Nr. 4, Dec. 2000, pp. 495-501.
	H. Artmann et l., "Monocrystalline SI Membranes For Pressure Sensors Fabricated By A Novel Surface Micromachining Process Using Porous Silicon", Proceedings of Spie, Memes Components and Applications for Industry, Automobiles, Aerospace and Communication II, January 28-29, 2003, San Jose, CA, Bd. 4981, pp. 65-70.
	G. Lammel et al. "Free-Standing, Mobile 3D Porous Silicon Microstructures", Sensors and Actuators A., Bd. 85, No. 1-3, August 25, 2000, pp. 356-360.

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.